Section I. (Amendments to the Specification)

At page 6, please replace paragraph [0018] with the following new replacement paragraph [0018]:

[0018] As illustrated, PANEL A includes a purge line 30 coupled with the purge gas source 34. The purge gas source 34 may comprise a cylinder or other supply container, or a "house" bulk purge source of purge gas for selective flow of purge gas through the purge line 30. The purge line 30 contains automatic valve AV-1, restricted flow orifice RFO-1, and an optional particle filter PF-1. The PANEL A main gas flow line 26 interconnects the process gas discharge manifold line 18 with a sub-atmospheric pressure gas supply vessel 14, as well as the purge gas manifold line 20 containing automatic valve AV-21 therein. The purge line 30 is coupled via line 31 to purge line 32 of PANEL B, so that purge gas source 34 serves both PANEL A and PANEL B.

Please replace the paragraph bridging pages 14 and 15, paragraph [0057], with the following new paragraph [0057]:

[0057] The purge effluent thus enters the dry scrubbing unit 42 and flows through the fixed bed material therein, and is discharged in process gas-depleted purge effluent discharge line 50 to the venturi pump 40. Drive gas, e.g., clean dry air (CDA), or other drive gas medium, is flowed to the venturi pump 40 in the direction indicated by arrow A through drive gas feed line 62 containing flow control valve 64. The flow control valve 64 may be an automatically actuated valve that is coupled by suitable signal transmission line and actuator elements to a CPU such as that shown in FIG. 1, to modulate the flow of drive gas consistent with the vacuum requirements of the gas cabinet in the purging operation.

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